

AMENDMENTS TO THE SPECIFICATION:

Please replace the paragraph beginning on line 10 of page 8 of the substitute specification with the following amended paragraph:

--Figure 1 shows the sensor and the control unit according to the present invention in a block diagram. Located in a control unit 10 is a sensor 1 that is connected via a digital line 6 to a processor 7. Processor 7 is connected via a data input/output to a memory 8. Processor 7 is connected via a data output to the remainder of restraint system 9. A so-called safety semiconductor [[11]] 5, i.e. a further processor or a monitoring circuit that also evaluates the sensor output values and can influence the enabling of restraint means, can be connected to digital line 6. Located in sensor 1 is a sensor element 2 for acquiring a measured variable, e.g. rotation rates or rotational accelerations. The sensor element can chiefly be a micromechanical sensor structure in which drive and detection occur capacitatively. Sensor element 2 is connected to a functional and monitoring module 3 where capacitance/voltage conversion, analog/digital conversion of the sensor signal, driving and regulation of the sensor oscillation, and sensor-internal monitoring functions can be implemented. Functional and monitoring module 3 is connected via a data output to a transmitter module 4. Transmitter module 4 is connected to digital line 6, which is embodied here as a so-called SPI (serial peripheral interface) line.--.

Please replace the paragraph beginning on line 33 of page 8 of the substitute specification with the following amended paragraph:

--Functional and monitoring module 3 thus also performs monitoring functions in sensor 1. The measured values are conveyed to transmitter module [[5]] 4. At a cycling rate predefined by the sensor circuit timing cycle, the fault patterns are continuously updated and can be continuously queried. The measured values in sensor 1 are incorporated into this fault pattern.--.